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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Attorney's Docket No.:

JG-SU-5222/500577.20072

U.S. Application No.:

International Application No.:

PCT/JP2004/016001

International Filing Date:

OCTOBER 28, 2004

28 OCTOBER 2004

Priority Date Claimed:

DECEMBER 01, 2003

01 DECEMBER 2003

Title of Invention:

MANUFACTURING METHOD OF SILICON WAFER

Applicant(s) for (DO/EO/US):

Sakae KOYATA and Kazushige TAKAISHI

Mail Stop PCT **Commissioner For Patents** P.O. Box 1450 Alexandria, VA 22313-450

INFORMATION DISCLOSURE STATEMENT

SIR:

Applicant herewith submits together with the simultaneously filed National Phase application of PCT/JP2004/016001, a copy of the International Search Report (PCT/ISA/210) dated February 15, 2005, citing some of the following references:

	Document Number	Date	Name and/or Country	English Translation and/or Equivalent
AA	6,099,748	08/08/2000	Netsu, et al.	
AL	60-197367	10/05/1985	Japan	Abstract only
AM	07-045564	02/14/1995	Japan	Abstract only
AN	11-171693	06/29/1999	Japan	Abstract only
AO	11-233485	08/27/1999	Japan	Abstract only
AP	2001-223187	08/17/2001	Japan	Abstract only
AQ	2003-100701	04/04/2003	Japan	Abstract only
AR	2003-203890	08/17/2003	Japan	Abstract only

Accompanying this Information Disclosure Statement and form PTO-1449 are copies of the documents including English Abstract and US equivalent. Document A9 is mentioned on page 3 of the substitute specification.

10/562236 IAPS Res'd PCT/PTO 22 DEC 2009

The USPTO waived the requirement under 37 C.F.R. §1.98(a)(2)(i) for submitting copies of US patents and US patent application publications in all U.S. applications filed after June 30, 2003. First pages of US documents only.

This submission is not an admission that the information disclosed in the documents is material to the patentability of the invention disclosed and/or claimed in the above-identified application.

Respectfully submitted,

JEG:ram 08/10/05

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Tel. (212) 521-5400

Enclosures:

Search Report (PCT/ISA/210);

PTO-1449

1 first page US Patents

7 foreign documents

7 English Abstracts

Reed Smith LLP

599 Lexington Avenue New York, NY 10022-7650

LIST OF PRIOR ART CITED BY APPLICANT (Filed on December 22, 2005)

JG-SU-5222/500577.20072

Docket No.

Examiner:

Applica	nt(s):	Sakae KOYA	TA and Kazı	ushige TAKAISHI					
Applica	tion No.	(In	ıt'i Appln No. PC1	T/JP2004/016001 28O	CT04) Grou	ıp:			
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Exam. Init		Document Number	Date	Name	Class	Sub- Class	Filing Date Appropriate		
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^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.